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Room 307

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Customer Number: 20277

#13/200

Masanobu IWASAKI, et al.

Docket No.: 50090-334

Confirmation Number:

06-01-04

Serial No.: 09/934,474

Group Art Unit: 3723

Filed: August 23, 2001

Examiner: H. Shakeri

POLISHING SOLUTION SUPPLY SYSTEM, METHOD OF SUPPLYING POLISHING SOLUTION, APPARATUS FOR AND METHOD OF POLISHING SEMICONDUCTOR SUBSTRATE AND METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

REQUEST FOR REFUND

Mail Stop Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

A refund in the amount of \$410.00 is hereby requested in the above-identified application for the following reason:

A Response to the Order Returning Undocketed Appeal to Examiner was filed on November 17, 2003. No Request for Extension of Time was required for this response. Please refer to the copy of the USPTO Pair Page attached. Please note that no other papers were filed that required Requests for Extension of Time. The fee of \$410.00 was erroneously charged on February 12, 2004 under Control No. 5.

Please immediately credit Deposit Account number 500417 in this amount.

410.00 CR

Respectfully submitted,

MCDERMOTT, WILL & EMERY

Registration No. 26,106

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Date: April 26, 2004



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PATENT APPLICATION INFORMATION RETRIEVAL





Other Links



| Se | earch results for a | pplication number | 00/024 474 |
|-------------------------------|---|---|---------------------------------------|
| Application Number: | 00004 4-4 | Customer Number | |
| Filing or 371(c) Date: | | Status | Reply Brief Noted |
| Application Type: | | Status Date: | Examiner |
| Examiner Name: | SHAKERI, HADI | Location: | TC 3700 CENTRAL |
| Group Art Unit: | 3723 | Location Date: | CP2-10C25 |
| Confirmation Number: | 8431 | Location Date: Earliest Publication No: | US 2002-0065022 / |
| Attorney Docket Number: | 50090-334 | Earliest Publication Date: | |
| Class/ Sub- Class: | 451/041 | Patent Number: | |
| First Named Inventor: | Masanobu lwasaki, Tokyo, (JP) | Issue Date of Patent: | |
| Title Of | Polishing solution supsolution, apparatus for | ply system, method of s and method of polishin of manufacturing semic | upplying polishing g semiconductor |

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Published Documents

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| Number | | File History |
|--------|------------|--|
| | Date | Contents Description |
| 36 | 04-07-2004 | Mail Miscellaneous Communication to Applicant |
| 35 | 04-06-2004 | Miscellaneous Communication to Applicant |
| 34 | 11-17-2003 | Miscellaneous Communication to Applicant - No Action Coun Miscellaneous Incoming Letter |
| 33 | 11-17-2003 | |
| 32 | 10-02-2003 | THE TOTAL OF THE CONTINUE OF T |
| 31 | 05-20-2003 | TERROR TANGETTING |
| 30 | 04-22-2003 | Order Returning Undocketed Appeal to the Examiner |
| 29 | 03-18-2003 | Appear Awaiting BPAI Docketing |
| 28 | 03-17-2003 | Mail Reply Brief Noted by Examiner |
| 27 | 01-27-2003 | Reply Brief Noted by Examiner |
| 26 | 01-22-2003 | Date Forwarded to Examiner |
| 25 | | Reply Brief Filed |
| 24 | 11-22-2002 | Mail Examiner's Answer |
| | 11-21-2002 | Examiner's Answer to Appeal Brief |
| 23 | 11-14-2002 | Date Forwarded to Examiner |

| 22 | 11-04-2002 | Appeal Brief Filed |
|----|------------|---|
| 21 | 09-04-2002 | Notice of Appeal Filed PANCH |
| 20 | 09-04-2002 | Request for Extension of Time - Granted |
| 19 | 07-26-2002 | Mail Advisory Action (PTOL - 303) |
| 18 | 07-28-2002 | Advisory Action (PTOL 303) 11 19: 59 |
| 17 | 07-25-2002 | Date Forwarded to Examiner |
| 16 | 07-18-2002 | Amendment after Final Rejection |
| 15 | 04-18-2002 | Mail Final Rejection (PTOL - 326) |
| 14 | 04-16-2002 | Final Rejection |
| 13 | 03-13-2002 | Date Forwarded to Examiner |
| 12 | 03-04-2002 | Response after Non-Final Action |
| 11 | 12-04-2001 | Mail Non-Final Rejection |
| 10 | | Non-Final Rejection |
| 9 | | Request for Foreign Priority (D.) |
| 8 | | Request for Foreign Priority (Priority Papers May Be Included) Information Disclosure Statement (IDS) Filed |
| 7 | | Case Docketed to Examiner in GAU |
| 6 | | Application Dispatched from OIPE |
| 5 | | Correspondence Address Change |
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